

## COPY OF PAPERS ORIGINALLY FILED

8/A 3/18/02

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	) Defere the Everyines	
Hiromichi Ohta, et al.	<ul><li>) Before the Examiner</li><li>)</li></ul>	
Application Social No.	) Jason Vincent V. de la	ı Peña
Application Serial No: 09/615,883	) Group Art Unit 1775	I hereby certify that this correspondence is being deposited with the United States
Filed July 14, 2000	)	Postal Service as first class mail in an envelope addressed to the Assistant Commissioner for Patents, Washington,
TITLE: LOW-RESISTANCE ITO THIN FILM AND METHOD FOR MANUFACTURING SUCH A FILM	) ) ) February 13, 2002	D.C. 20231 on:  February 13, 2002 (Date of Deposit)
	)	Vincent O. Wagner Name of Registered Representative
		Signature
		February 13, 2002 Date of Signature

**RESPONSE** 

Commissioner of Patents Washington, D.C.

In response to the Office Action dated August 14, 2001 please enter the following amendments and consider the accompanying remarks. Filed concurrent with this Response is Request for a three-month Extension of Time to respond this Office Action and an Information Disclosure Statement. Additionally, please charge any fees that may be due to Deposit Account No. 23-3030, but do not include any payment of issue fees that are or may become due.

03/05/2002 SFELEKEI 00000020 09615883

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